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U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FIL. DATE IF APPROP.
SDE	6,177,301	01/23/01	Jung	438	150	05/13/99
SDE	6,235,614	05/22/01	Yang	438	486	05/13/99
SDE	6,274,888	08/14/01	Suzuki et al.	257	72	01/10/00
FOREIGN PATENT DOCUMENTS						
	DOCUMENT NUMBER	DATE	COUNTRY/NAME	CLASS	SUB CLASS	TRANSLATION YES NO
OTHER DOCUMENTS						
SDE	Article entitled, "Phase Transformation Mechanisms involved in Excimer Laser crystallization of Amorphous Silicon Films", by Im et al., published in Appl. Phys. Lett. 63 (14), 4 October 1993, pp 1969-1971					
SDE	Article entitled, "Sequential Lateral Solidification of Thin Silicon Films on SiO ₂ ", by Sposili et al., published in Appl. Phys. Lett. 69 (19) 4 November 1996, pp 2864-2866					
SDE	Article entitled, "Controlled Super-Lateral Growth of Si Films for Microstructural Manipulation and Optimization", by Im et al., published in Phys. Stat. Sol. (a) 166, 603 (1998), pp 603-617					
SDE	Article entitled, "Crystalline Si Films for Integrated Active-Matrix Liquid-Crystal Displays", by Im et al., published in MRS Bulletin/ March 1996, pp 39-48					
SDE	Article entitled, "Low-Temperature Single-Crystal Si TFT's Fabricated on Si Films Processed via Sequential Lateral Solidification", by Crowder et al., published in IEEE Electron Device Letters, Vol. 19, No. 8, August 1998, pp 306-308					
SDE	Article entitled, "Single-Crystal Si Films for Thin-Film Transistor Devices", by Im et al., published in Appl. Phys. Lett. 70 (25), 23 June 1997, pp 3434-3436					
EXAMINER <i>Stanetta Baur</i>			DATE CONSIDERED <i>2/22/04</i>			